

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: LEE, Ho  
Assignee: SAMSUNG ELECTRONICS CO., LTD.  
Title: CHEMICAL VAPOR DEPOSITION APPARATUS  
Application No.: 10/750,023 Filing Date: December 31, 2003  
Examiner: Jeffrie Robert Lund Group Art Unit: 1763  
Docket No.: AB-1350 US Confirmation No.: 9344

San Jose, California  
June 29, 2005

Mail Stop Amendment  
COMMISSIONER FOR PATENTS  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Dear Sir:

In response to the Office Action having a mailing date of March 29, 2005, please amend the application as set forth below.

**Amendment to the Specification** begins on page 2 of this paper.

**Claim listing** begins on page 3 of this paper.

**Remarks** begin on page 5 of this paper.

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